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concord

a step of irradiating an evaluation mark having diffraction grating patterns formed on a substrate with illumination light by way of the illumination optical system and observing the evaluation mark by way of the projection optical system to obtain a brightness of the evaluation mark; and

a step of measuring the displacement of the optical axis based upon the relationship between the brightness of [the] an image of the evaluation mark and a direction of the diffraction grating patterns of the evaluation mark.

2. (Amended) The method of measuring the displacement of the optical axis according to claim 1, wherein

the evaluation mark is composed of at least two gratings connected together and arranged in series with each other, each having parallel bars that extend in a direction different from those of any other grating.

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9. (Amended) An optical microscope comprising:

an illumination optical system through which illumination light to be applied to an evaluation mark passes;

a projecting optical system through which the illumination light reflected from the evaluation mark passes; and

a removable and rotatable shield means provided at a pupil of the projection optical system and having a shield area, the shield area being asymmetric relative to normal light of the illumination light from a substrate.

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